

	Type	L #	Hits	Search Text	DBs
1	IS&R	L1	2	(("4012648") or ("3913195")) .PN.	USPAT
2	BRS	L2	262	(mems or microelectromechanical or "micro electromechanical") adj4 (oscillat\$3 or vibrat\$3 or resonat\$3)	USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TD B
3	BRS	L3	50	mircoresonator or "micro resonator"	USPAT
4	BRS	L4	75	mircoresonator or "micro resonator"	USOCR; EPO; JPO; DERWEN T; IBM_TD B

[Search Summary]

Results of searching in PCT (Full Text) for:

((mems or microelectromechanical or "micro mechanical" or microresonator or "micro resonator")) and ((oscillator or resonator or vibration or oscillation or vibrator)) and cantilever and ((mounting or pedestal)): 61 records

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((mems or microelectromechanical or "micro mechan

Title

1. [\(WO 2005/017937\) SENSOR ARRAY FOR MEASURING PLASMA CHARACTERISTICS IN PLASMA PROCESSING ENVIRONMENTS](#)
2. [\(WO 2005/008443\) DISTRIBUTED SENSOR ARRAY FOR FLUID CONTAMINANT MONITORING](#)
3. [\(WO 2005/006273\) PORTABLE MOTION DETECTOR AND ALARM SYSTEM AND METHOD](#)
4. [\(WO 2005/002858\) A THERMAL ACTUATOR AND LIQUID DROP EMITTER](#)
5. [\(WO 2005/001903\) PULSE DRIVE OF RESONANT MEMS DEVICES](#)
6. [\(WO 2004/095696\) TEMPERATURE COMPENSATION FOR SILICON MEMS RESONATOR](#)
7. [\(WO 2004/095152\) VIBRATION MONITORING IN OPTICAL AND OPTO-ELECTRONIC BEAM GUIDING SYSTEMS](#)
8. [\(WO 2004/094956\) QUANTUM TUNNELLING TRANSDUCER DEVICE](#)
9. [\(WO 2004/084131\) MEMORY DEVICES](#)
10. [\(WO 2004/083798\) TEMPERATURE SENSING DEVICES, SYSTEMS AND METHODS](#)
11. [\(WO 2004/080886\) MEMS DEVICES ON A NANOMETER SCALE](#)
12. [\(WO 2004/055935\) VARACTOR APPARATUSES AND METHODS](#)
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13. [\(WO 2004/068218\) OPTICAL BEAM SCANNING SYSTEM FOR COMPACT IMAGE DISPLAY OR IMAGE ACQUISITION](#)
14. [\(WO 2004/055935\) VARACTOR APPARATUSES AND METHODS](#)
15. [\(WO 2004/051744\) MEMS CONTROL CHIP INTEGRATION](#)
16. [\(WO 2004/037712\) METHOD FOR PRODUCING A PACKAGED INTEGRATED CIRCUIT](#)
17. [\(WO 2004/025676\) MECHANICALLY BI-STABLE MEMS RELAY DEVICE](#)
18. [\(WO 2004/012201\) METHOD OF AND APPARATUS FOR CALIBRATING CANTILEVERS](#)
19. [\(WO 2004/001807\) CONSTRUCTION STRUCTURES AND MANUFACTURING PROCESSES FOR PROBE CARD ASSEMBLIES AND PACKAGES HAVING WAFER LEVEL SPRINGS](#)
20. [\(WO 03/072486\) MEMS DEVICES AND METHODS OF MANUFACTURE](#)
21. [\(WO 03/069355\) ACCELERATION SENSOR](#)
22. [\(WO 03/049592\) GATEWAY PLATFORM FOR BIOLOGICAL MONITORING AND DELIVERY OF THERAPEUTIC COMPOUNDS](#)
23. [\(WO 03/047307\) A MINIATURE CONDENSER MICROPHONE AND FABRICATION METHOD THEREFOR](#)

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microresonator oscillator pedestal

AND

AND

AND

AND

AND

AND

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-

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AND

AND

AND

AND

AND

AND

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 OR **AND**

cantilever

 AND **AND**

pedestal mounting

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mems microelectromechanical microresonator microoscillator

OR**AND**

cantilever

AND**AND****OR****AND**

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